



520.34403CV4

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant(s): T. MASUDA, et al
Serial No.: 09/421,043
Filed: October 20, 1999
For: PLASMA ETCHING APPARATUS AND PLASMA ETCHING METHOD
Group: 1763
Examiner: A. Mulero

AMENDMENT

Mail Stop: Amendment (Fee)
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

April 29, 2005

Sir:

The following amendments and remarks are respectfully submitted in connection with the above-identified application, in response to the Office Action dated November 29, 2004. The amendments are listed below and set forth on the following pages.

Amendment of the Claims;

Remarks are included following the amendments; and